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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Sukharev, Catabay  
Title: Viscous Electropolishing System  
Filing date: 2001.12.21  
Express mail number: EL 511 138 675 US  
Attorney docket: 01-822



INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97


Assistant Commissioner for Patents  
Washington DC 20231

Sir:

The enclosed documents are submitted in compliance with 37 C.F.R. §§ 1.97 and 1.98. Also enclosed is a form PTO-1449 listing the citations. By this submission Applicant is not admitting the materiality of these citations; they are merely submitted to ensure full compliance with 37 C.F.R. § 1.56.

Sincerely,

LUEDEKA, NEELY & GRAHAM, P.C.

By:   
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2001.12.21

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FORM PTO-1449 INFORMATION DISCLOSURE CITATIONS IN AN APPLICATION		Atty Docket: 01-822	Serial #:
		Applicant: Sukharev, Catabay	
		Filing Date: 2001.12.21	Group:

**U.S. PATENT DOCUMENTS**

Examiner Initial	Cite #	Document Number	Date	Name	Class	Sub-Class	Filing Date
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**FOREIGN PATENT DOCUMENTS**

Examiner Initial	Cite #	Document Number	Date	Country	Class	Sub-Class	Translation
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**OTHER NON-PATENT DOCUMENTS**

Examiner Initial	Cite #	Author, title, date, pertinent pages, etc.
	1	Wang et al., <i>Stress-free polishing advances copper integrated with ultralow-k dielectrics</i> , Solid State Technology, pp.101-106, October 2001.

Examiner	Date Considered:
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.	